

-A Satellite Workshop at IPAC-2010 -
**Superconducting RF Cavity Technology
and Industrialization**

Industrialization Study with Japanese Industries

Eiji Kako (KEK)

in cooperation with Japanese Industries

**IPAC-2010 Satellite Workshop, Kyoto,
May 23, 2010**

- **Introduction**
 - Industrial models assumed for the ILC SCRF cavities
- **Industrialization Study in cooperation with Japanese Industries**
 - Manufacturing process and facilities required
 - Industrial engineering examples



A Model for Industrialization

- A model for 9-cell cavity productions
 - 15,764 + spare + production back-up (~ 10%)
 - → ~ **18,000** cavities / **4~5** years
- Possible models for manufacturing
 - **Single consortium/vendor**
 - **Three regional consortiums/vendors**
 - **Six (or more) consortiums/vendors**
 - **< 3,000 >** cavities / vendor
 - **< 3 >** cavities / day / vendor
(assuming 5 years and 200 days/year)



Industrialization Study in Japan

- KEK started the ILC industrialization study in cooperation with Japanese Industries
- **KEK:**
 - Provides process models and required times
- **Industries:**
 - Study manufacturing model and facilities required, and
 - Report examples of industrialization experiences as references for further studies



Standard process selected in cavity production and the yield

	Standard Cavity Recipe
Fabrication	Nb-sheet (Fine Grain)
	Component preparation
	Cavity assembly w/ EBW (w/ experienced vendors)
Process	1st (Bulk) Electro-polishing (~150um)
	Ultrasonic degreasing with detergent, or ethanol rinse
	High-pressure pure-water rinsing
	Hydrogen degassing at > 600 C
	Field flatness tuning
	2nd Electro-polishing (~20um)
	Ultrasonic degreasing or ethanol
	High-pressure pure-water rinsing
	Antenna Assembly
	Baking at 120 C
Cold Test (vert. test)	Performance Test with temperature and mode measurement (1st / 2nd successful RF Test)



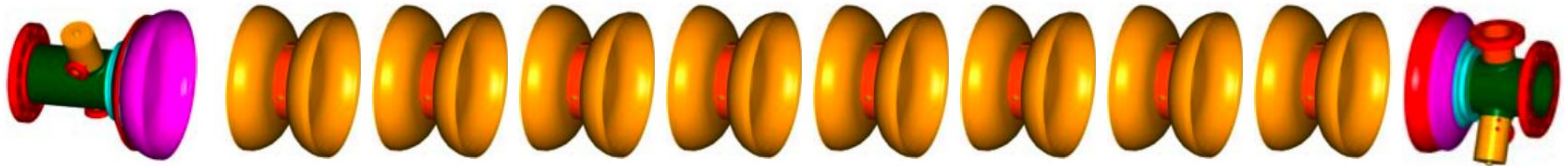
Example of cavity fabrication process

EBW of dumb-bell



24 dumb-bells / day

EBW of 9-cell cavity



3 cavities / day

Welding of Ti helium jacket







3 cavities / day

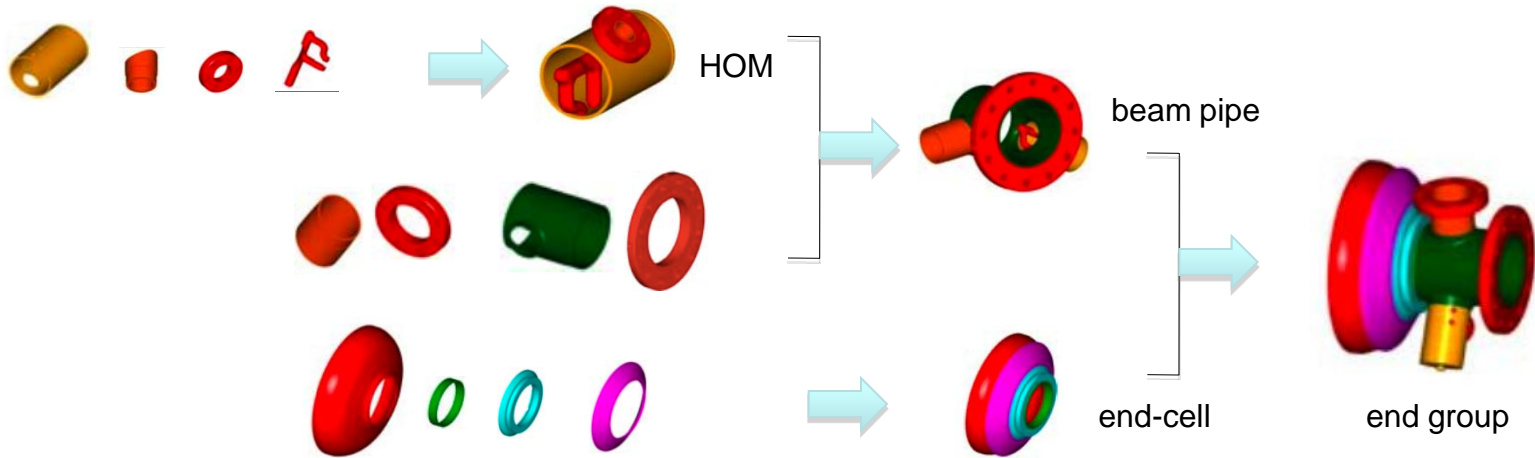


Example of cavity fabrication process

Machining of end-group parts

-  Nb-Ti flange (6/cavity) 18 / day
-  Nb beam tube (2/cavity) 6 / day
-  Burring of ports (4/cavity) 12 / day
-  Trimming of half-cell (18/cavity) 54 / day

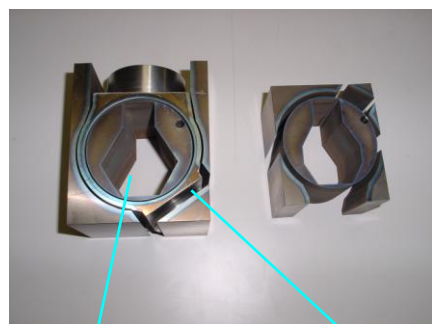
EBW of end-group parts



6 end-groups (both sides) / day



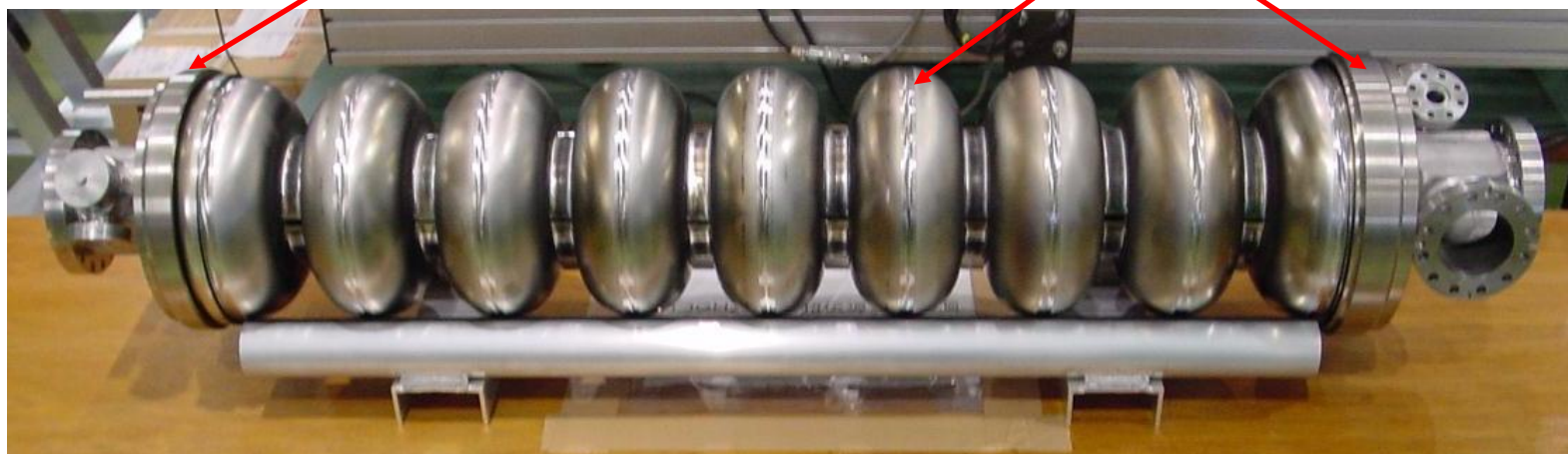
Cavity Fabrication Process



HOM coupler

End-groups

Center-cells
(Tokyo Denkai ; RRR~300 Nb)





Cavity Processing for Vertical Tests



Barrel Polishing
~100 μm



pre-EP
~10 μm



Initial EP
100 μm



Anneal
750°C, 3h



Pre-tuning
fo, flatness, HOM filter



Final EP
50 μm
(20, 30 μm)



Hot Rinse with
ultra-sonic bath
50°C, 1h



HPR 8MPa, 6~16h



Assembly



Baking 120°C, 40h

(HF or H₂O₂ Rinse, 1h)

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Boundary Conditions

+ We evaluate an ideal production facility from cavity fabrication to cryomodule assembly to produce **600 cavities per year** by using a factory production simulation analysis.

[assumption]

- Consider **only process time** including preparing time to machining, welding, vertical test, surface treatment and cryomodule assembly excluding conveying time of parts and assemblies and costs of labors.
- Assumed cavity yield at **35MV/m = 80%** through first cavity processing and **50%** after repairing and second cavity processing.
- Based on **16 hours of actual run time (2 shifts) per day** for each machining and process.
- Evaluate the **number of machines and apparatus** to satisfy the production rate by use of production simulation code.
- Machining, welding and other process would use special jigs to handle multiple subassemblies for a given process cycle.

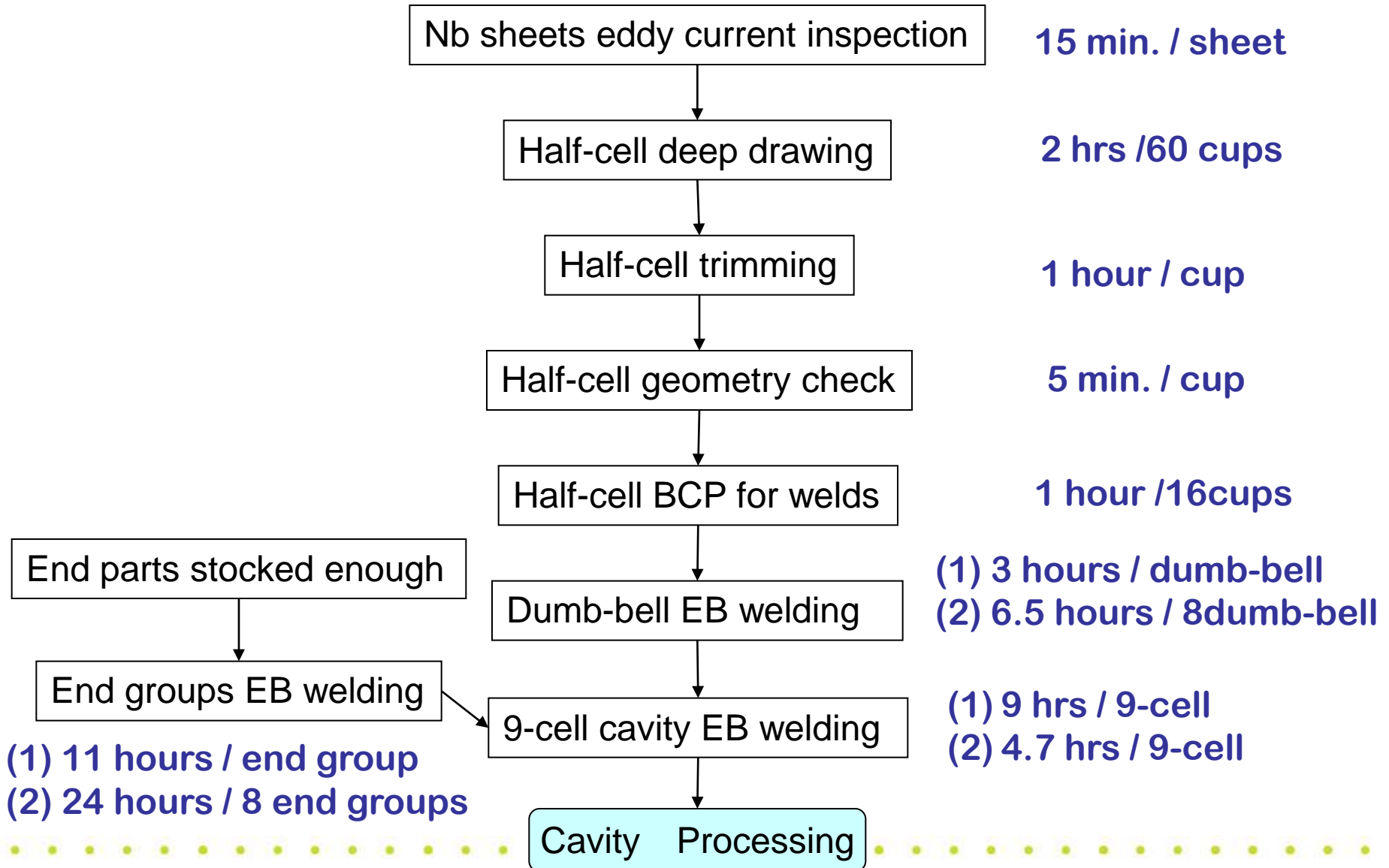


Mass Production Models

- **Case 1**
 - Laboratory R&D scheme
 - 1 seam / one welding cycle
- **Case 2**
 - Current production scheme at some industries
 - Dumb-bell: 8 seams / one welding cycle
 - 8 dumb-bell + 2 end-group (= 9-cell cavity) EBW /one welding cycle
- **Case 3**
 - Simple mass production model
 - 8 end-group / one welding cycle
 - 8 dumb-bell + 2 end-group (= 9-cell cavity) EBW /one welding cycle
- **Case 4, (in Preparation)**
 - 8 end-group / one welding cycle
 - 8 x 9-cell cavity EBW / one welding cycle



Cavity Fabrication





Numbers of processes trade-off

	Yield %	Fabrication of Dumb-bell with EBW	Fabrication of End group EBW	Assemble 9-cell Cavity With EBW	Number of machines and processes required		
					EB Welding	Vertical Test	Electro-polishing
Case1 R&D phase	100	1 seam / welding cycle (3 hrs/3 cycle)	1 seam / welding cycle (11 hrs / 11 cycle)	one 2(4,8)-cell / welding cycle (9 hrs/9 cycle)	12	6 7	6
	90						
Case2 Current production	100	8 dumb-bell / welding cycle (6.5/8 hrs/3 cycle)	8 end-group / welding cycle (46.7/8 hrs/11 cycle)	one 9-cell / 2 welding cycle (4.7 hrs / 2 cycle)	8 → 7*	6 7	6
	90						
Case3 Mass Production Study	100	8 dumb-bell / welding cycle (6.5/8 hrs/3 cycle)	8 end-group / welding cycle (46.7/8 hrs/11 cycle)	one 9-cell / 2 welding cycle (4.7 hrs / 2 cycle)	5 → 4*	6 7	6
	90						

* In case of common EBW machines for dumb-bell and end-group



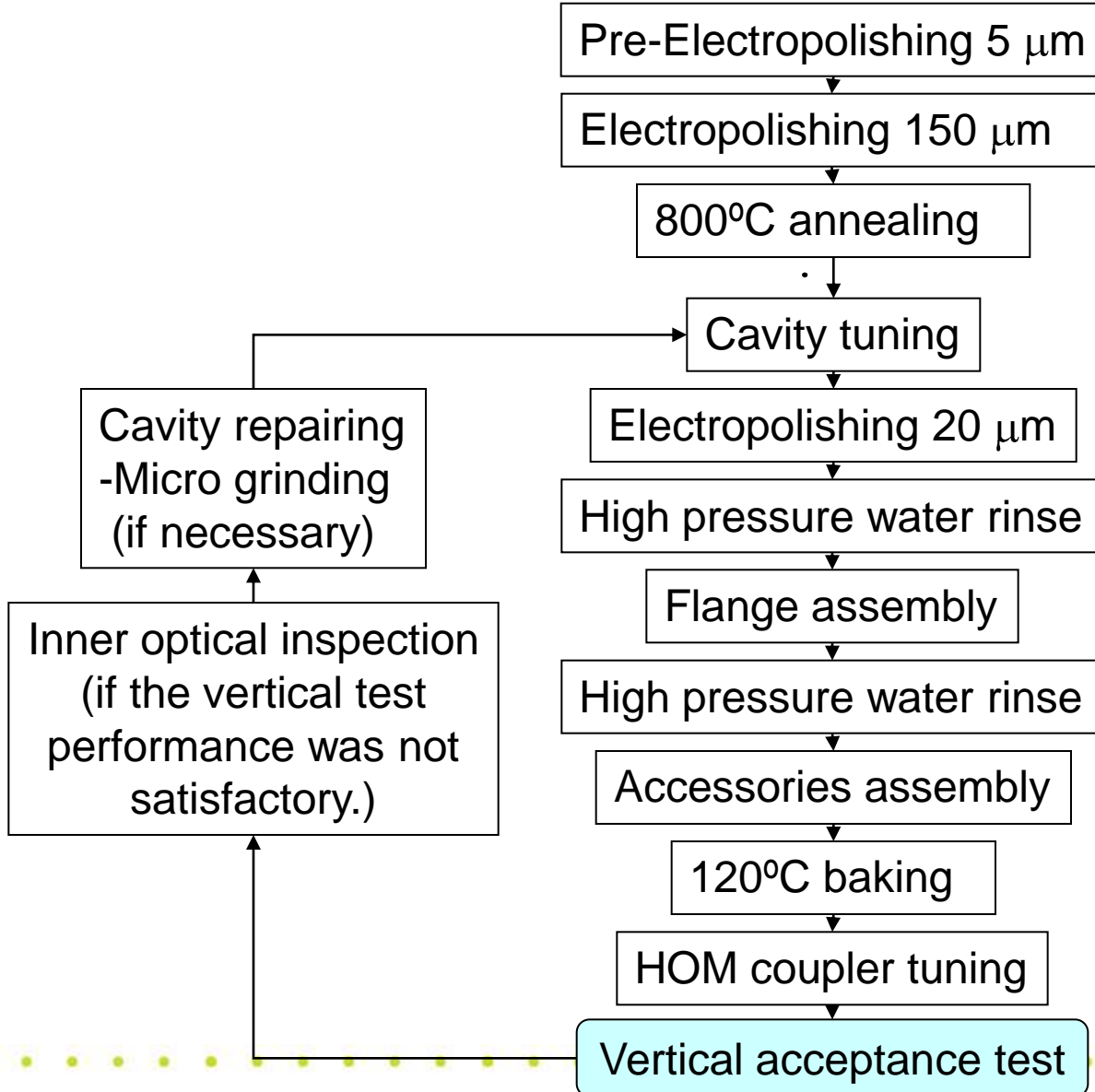
Number of Cavity Fabrication Facilities Required

	actual run time (2 shifts) per day for each process	Number of machines (processes)					
		Case1		Case2		Case3	
		Yield %					
		100	90	100	90	100	90
Nb sheets eddy current inspection	16	1	1	1	1	1	1
Half-cell deep drawing	8	1	1	1	1	1	1
Half-cell trimming	16	3	3	3	3	3	3
Half-cell geometry check	8	1	1	1	1	1	1
Half-cell BCP for welds		1	1	1	1	1	1
Dumb-bell EB welding	16	5	5	2*	2*	2**	2**
End groups EB welding		5	5	5*	5*	2**	2**
9-cell cavity EB welding		2	2	1	1	1	1

* 2+5 → 6, ** 2+2 → 3
in case of common EBW machine



Cavity Processing



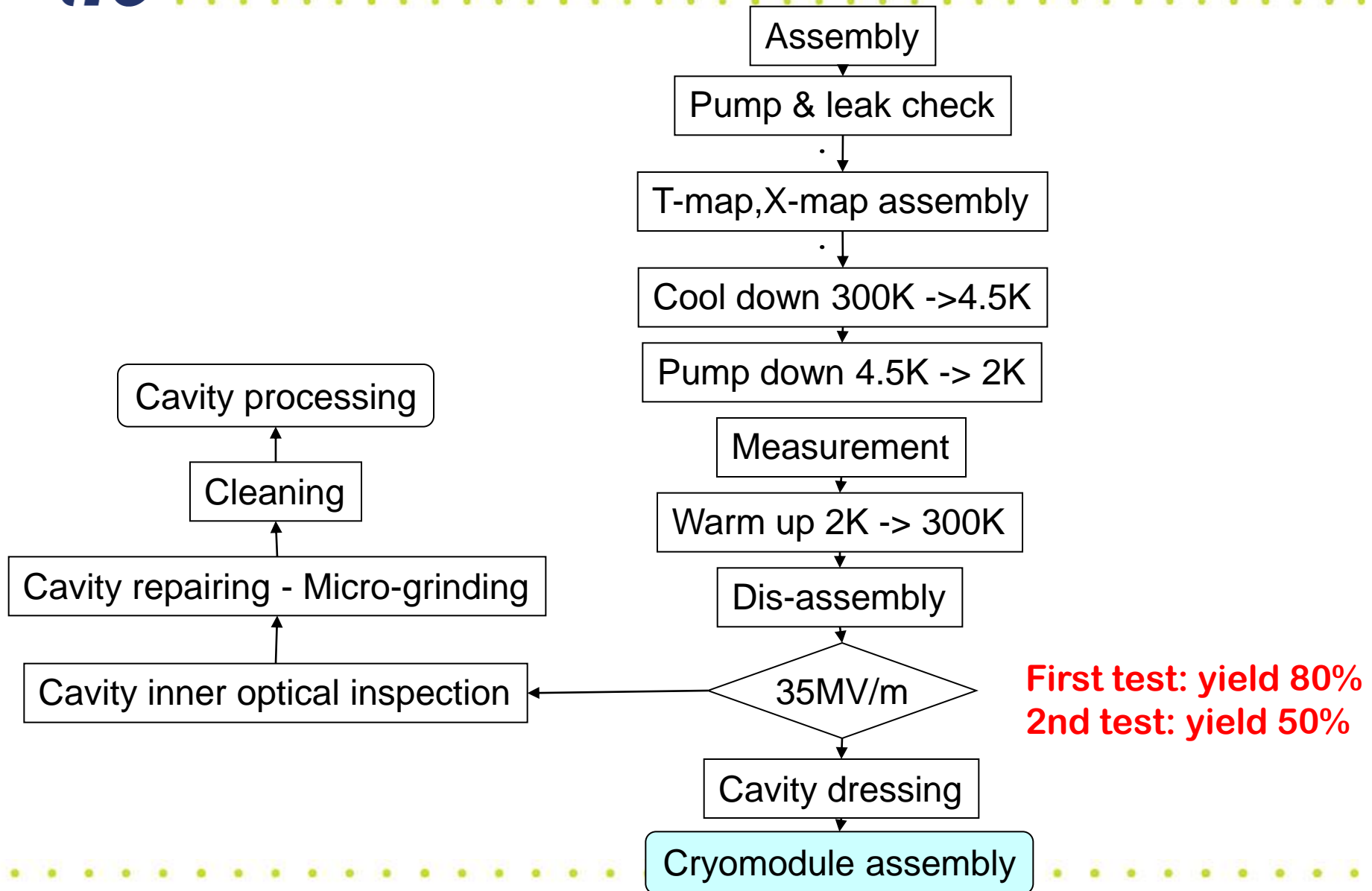


Cavity Processing

	actual run time (2 shifts) per day for each process	Number of machines (processes)					
		Case1		Case2		Case3	
		Yield %					
		100	90	100	90	100	90
Pre-Electropolishing	16	2	2	2	2	2	2
Electropolishing 150 μ m		6	6	6	6	6	6
Electropolishing 20 μ m							
800 $^{\circ}$ C annealing	24	2	2	2	2	2	2
Cavity tuning	16	2	2	2	2	2	2
Flange assembly	8	1	1	1	1	1	1
High pressure water rinse	16	2	2	2	2	2	2
Assembly of accessories		2	2	2	2	2	2
High pressure water rinse		2	2	2	2	2	2
120 $^{\circ}$ C baking	24	2	2	2	2	2	2
HOM coupler tuning	16	1	1	1	1	1	1



Vertical Acceptance Test





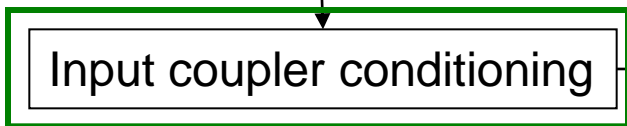
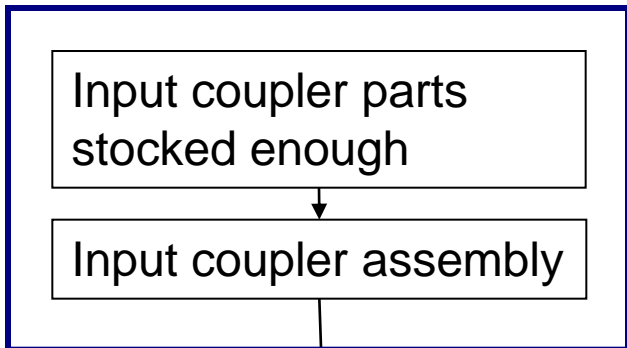
Vertical Acceptance Test

	actual run time (2 shifts) per day for each process	Number of machines (processes)					
		Case1		Case2		Case3	
		Yield %					
		100	90	100	90	100	90
Assembly	16						
Pump & leak check		2	2	2	2	2	2
T-map,X-map assembly							
Cool down 300K ->4.5K							
Pump down 4.5K -> 2K		6	7	6	7	6	7
Measurement							
Warm up 2K -> 300K							
Disassembly		1	1	1	1	1	1
Cavity inner optical inspection	8	1	1	1	1	1	1
Cavity repairing - Micro-grinding	16	1	1	1	1	1	1
Cleaning	8	1	1	1	1	1	1



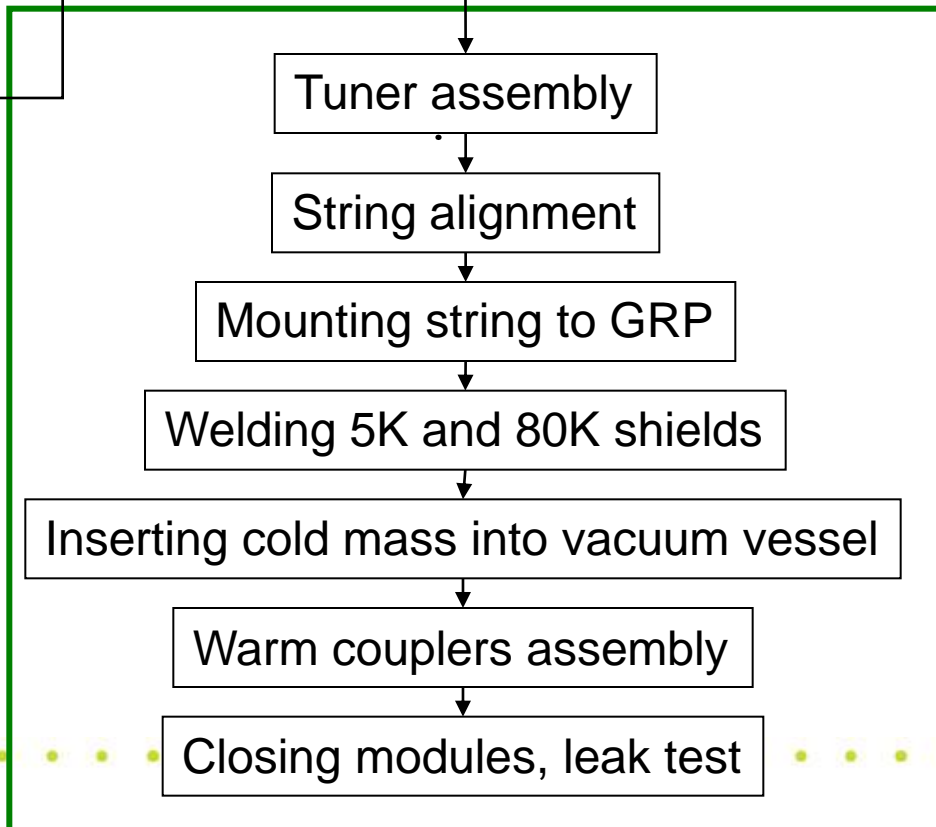
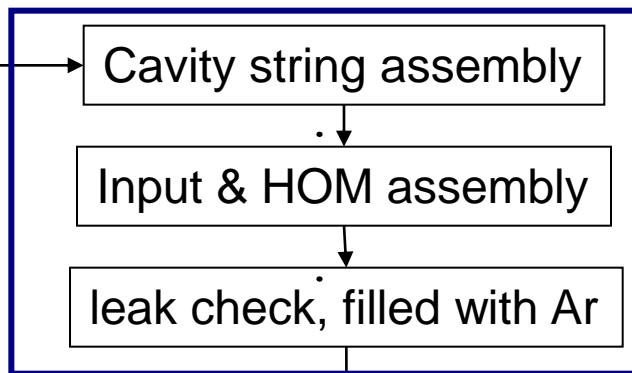
Cryomodule Assembly

Clean room



RF test-stand area

Clean room



Cryomodule
assembly area



Cryomodule Assembly

	actual run time (2 shifts) per day for each process	Number of machines (processes)					
		Case1		Case2		Case3	
		Yield %					
		100	90	100	90	100	90
Cavity dressing	16	5	5	5	5	5	5
Cold coupler assembly		5	5	5	5	5	5
Input coupler conditioning		2	2	2	2	2	2
String assembly							
Input & HOM assembly		1	1	1	1	1	1
leak check, filled with Ar							
Tuner assembly							
String alignment							
Mounting string to GRP							
Welding 5K and 80K shields		4	4	4	4	4	4
Inserting cold mass into vacuum vessel							
Warm couplers assembly							
Closing modules, leak test							



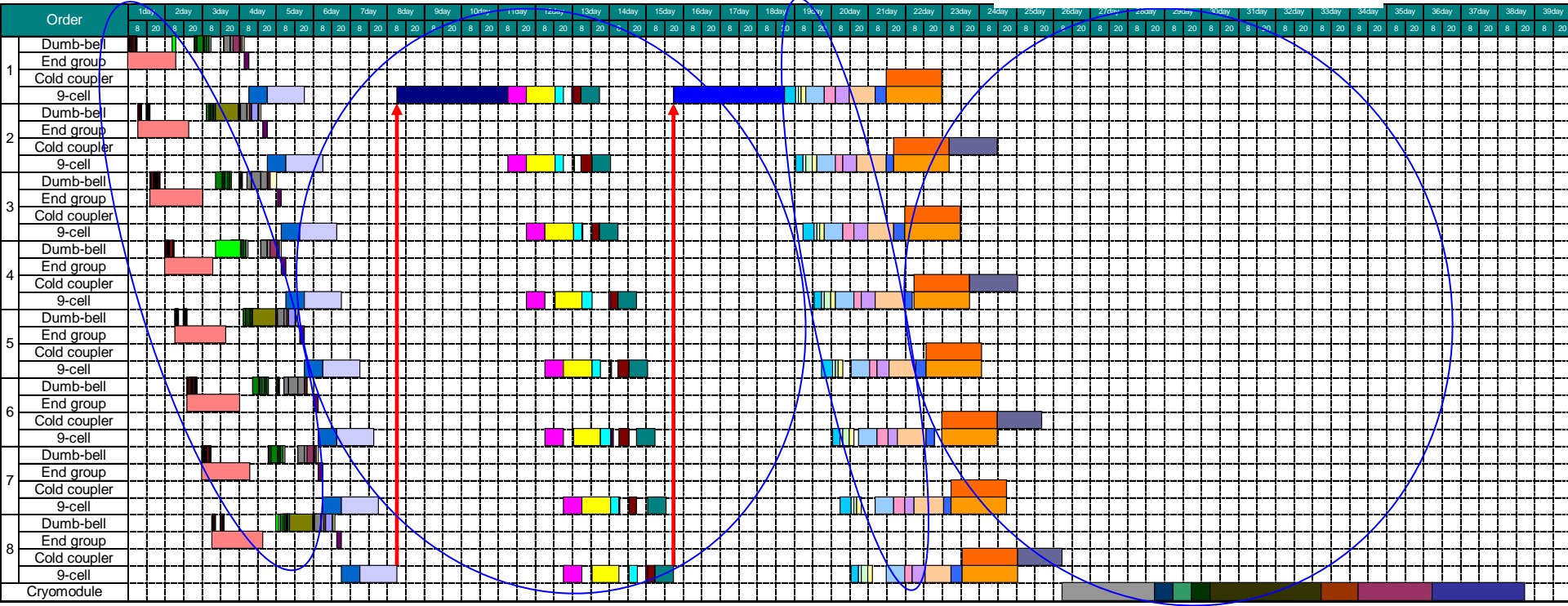
Example of Production Process (Case1)

Cavity Fabrication

Cavity Processing

Vertical Test

Cryomodule Assembly



- | | | | | |
|-----------------------------------|-------------------------|--------------------------|-----------------------|--|
| Nb sheets eddy current inspection | Pre-Electropolishing | Assembly | Cavity dressing | Tuner assembly |
| Half-cell deep drawing | EP110mm | Pump & leak check | Cold coupler assembly | String alignment |
| Half-cell trimming | 800°C annealing | T-map,X-map assembly | Conditioning | Mounting string to GRP |
| Half-cell geometry check | Cavity tuning | Cool down 300K ->4.5K | String assembly | Welding 5K and 80K shields |
| Half-cell BCP for welds | EP40mm | Pump down 4.5K -> 2K | | Inserting cold mass into vacuum vessel |
| Dumb-bell EB welding | HPR | Measurement | | Warm couplers assembly |
| 9-cell cavity EB welding | Flange assembly | Warm up 2K -> 300K | | Closing modules, leak test |
| 9-cell cavity EB welding | HPR | Dis-assembly | | |
| 9-cell cavity EB welding | Assembly of accessories | Inner optical inspection | | |
| 9-cell cavity EB welding | 120°C baking | Micro-grinding | | |
| End groups EB welding | HOM coupler tuning | Cleaning | | |

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Mass Production Engineering Experience

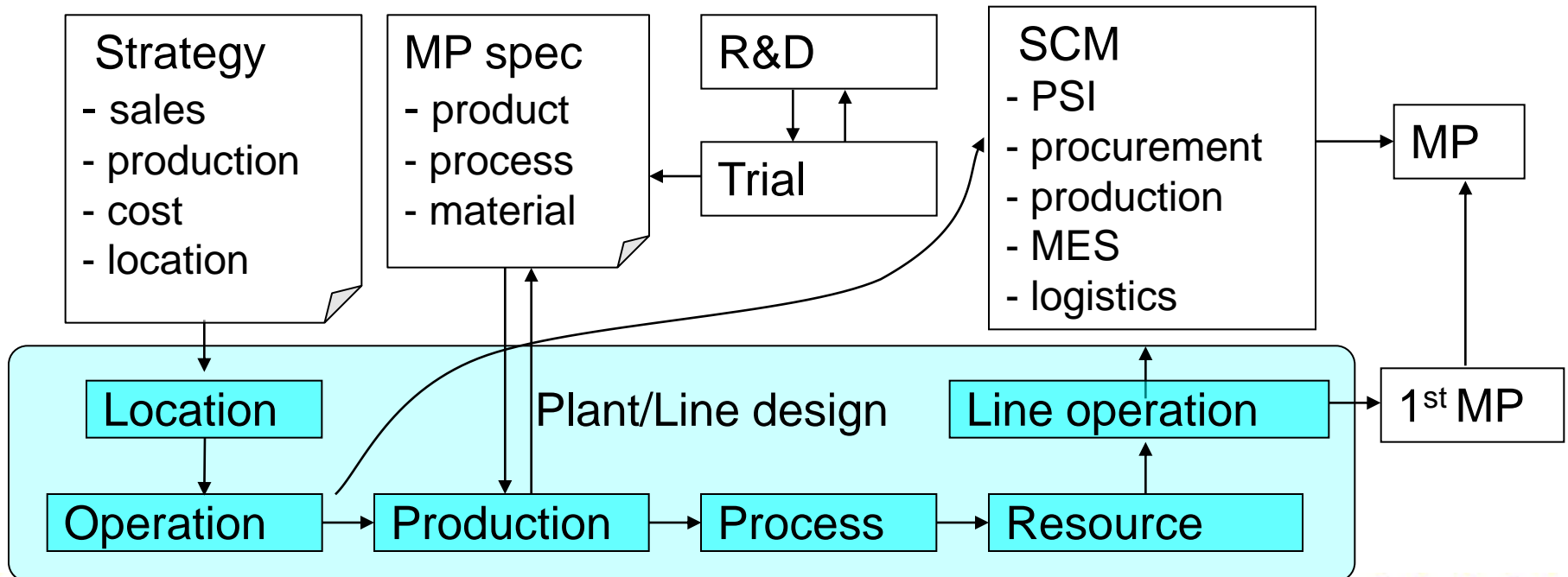
1. Basic method for Mass Production line design
2. Example Mass Production line design like ILC
3. Consortium Experience with SELETE



Basic method for Mass production line design

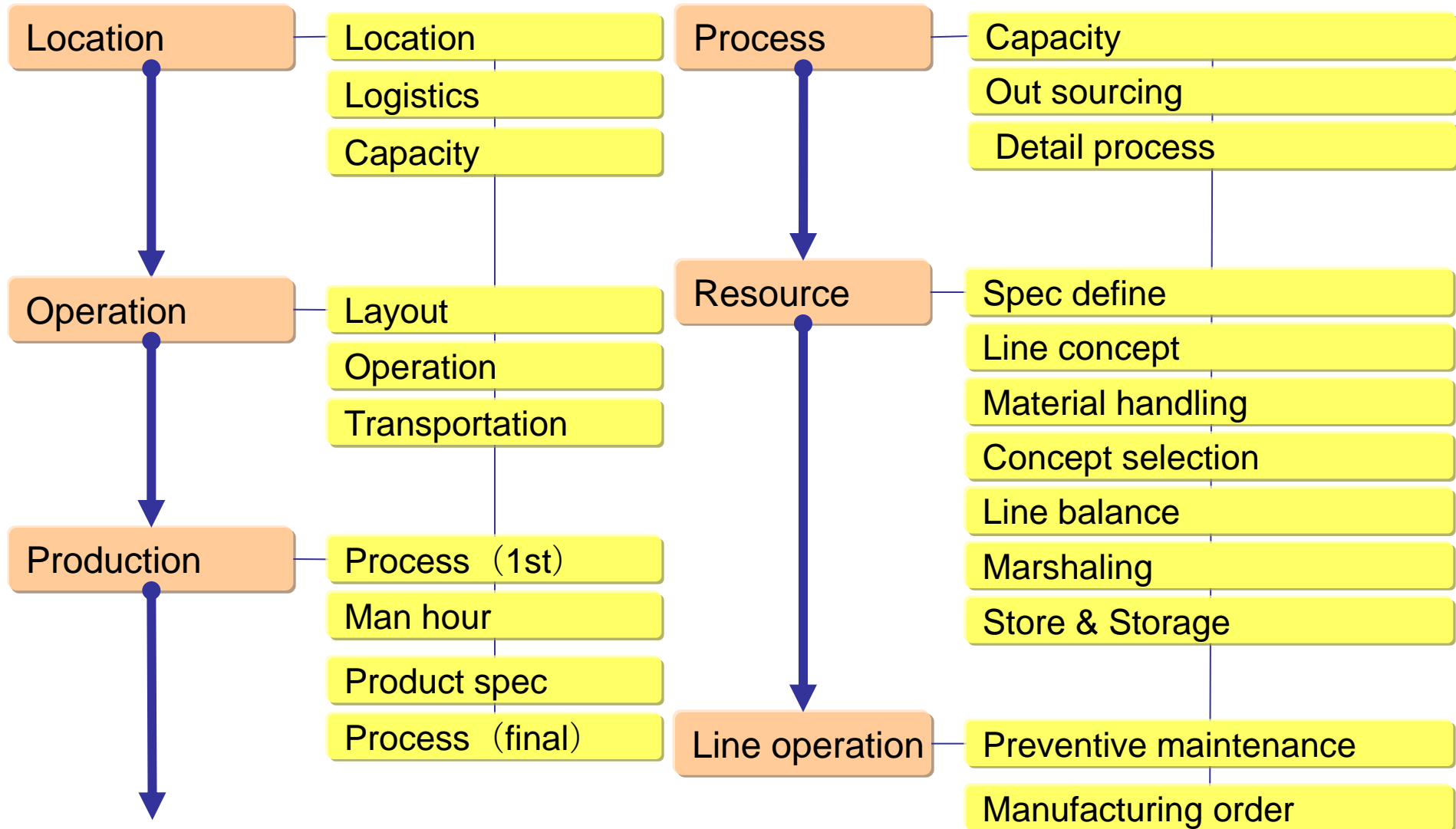
- Start line: Outline of MP spec finished
- Objective: Cost(Equipment investment, labor cost) and delivery(lead time)
- KPI:
 - Quality
 - Cost ⇒ estimate on cost simulation
 - Delivery ⇒ estimate on manufacturing simulation
- Cycle time: 2minutes(=200p/8Hr)
- Motif: Semiconductor, LCD, HDD
- Production term: many production model

PSI: Purchase & Production, Sales, Inventory
MES: Manufacturing execution system
SCM: Supply chain management





Basic method for Mass production line design





Example of Mass production line of new product

■ Abstract

- Product: Electrical control unit
- Amount: 100Kp/Y
- Investment: 500million yen
- Sales Price: 100k yen
- Customer: USA
- Return term: 5years

■ PJ

- Steering committee
- Committee: 1time/M
 - Confirmation of status
 - Confirmation of problem

PJL,SPJL

- MP line WG
- Process planning
 - Development of Equipment
 - Equipment investment plan

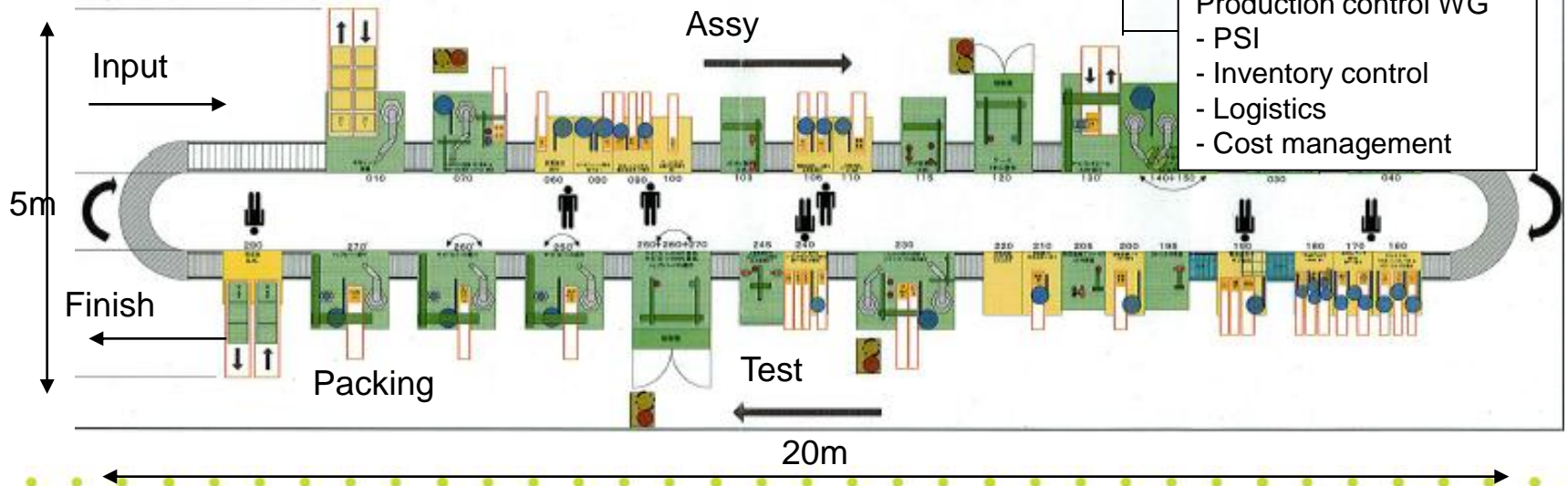
- QC WG
- Traceability system
 - QMS
 - Process QC

- Procurement WG
- CR
 - Select of supplier

- Production control WG
- PSI
 - Inventory control
 - Logistics
 - Cost management

QMS: Quality management system
 QC: Quality control
 CR: Cost reduction

■ MP line idea





SELETE as a Consortium

Semiconductor Leading Edge Technologies, Inc.

SELETE was founded in 1996 as a consortium for development of production technologies using 300mm wafer equipments with equal capital investment from 10 semiconductor manufacturers.

FUJITSU, HITACHI, MATSUSHITA, MITSUBISHI, NEC, OKI, SANYO, SHARP, SONY, TOSHIBA

Investment (500 million yen each company)

■ Objective:

Reduce of R&D cost for higher difficulty and R&D cost of semiconductor technologies

■ Target :

Evaluation and improvement for 300 mm wafer mass production equipment.

■ Output:

Evaluate 137 equipments necessary to all production technologies for 300 mm mass production plant.

Equipment performance target unify to International Sematech(I300I).



SUMMARY

- ILC cavity industrialization models have been investigated in cooperation with Japanese Industries,
 - **A production model: 3 cavities/day for 5 years**
- Based on each process time determined by KEK, the required industrial facilities have been investigated,
- Dumb-bell process may be a critical pass to determine number of EBW facilities, and multiple seams per one welding cycle may help to reduce the number of EBW facilities,
- Full production model in preparation to be studied,
- Workshop layout and number of workers are to be further studied, as well as the cost-effective fabrication is to be investigated.



Acknowledgements

- *We would thank*
 - Japanese industries (MHI, Toshiba, and Hitachi) manufacturing SCRF cavities for their kindest cooperation for the industrialization studies.